



TIAF/ATW

**RESPONSE UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE REQUESTED
EXAMINING GROUP 2818
PATENT
Attorney Docket No. 04329.3238**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Gaku MINAMIHABA et al.) Group Art Unit: 2818
Application No. 10/771,060) Examiner: Goodwin, David J.
Filed: February 4, 2004) Confirmation No.: 2231
For: POLISHING PAD AND METHOD OF) Mail Stop AF
MANUFACTURING)
SEMICONDUCTOR DEVICES)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

AMENDMENT AFTER FINAL

In reply to the Final Office Action mailed August 25, 2006, the period for response to which extends through November 27, 2006 (November 25th being a Saturday), and pursuant to 37 C.F.R. § 1.116, Applicants propose that this application be amended as follows:

Amendments to the Claims are reflected in the listing of claims in this paper.

Remarks/Arguments follow the amendment section of this paper.